

# On pulsed RF measurements

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# Motivation

- Improved SiGe HBT performance within the DOT5  
→ new spectrum of sub-millimeter-wave applications [1]
- Higher performance due to down-scaling
- Issue: DC and S-par measurements are more affected by self-heating → device temperature variation is generally unknown → model parameter extraction difficult
- Solution: Pulsed DC and S-par measurements
  - Pulse width smaller than thermal time constant of transistor  
→ no significant change in temperature during measurement
  - Exploration of save operating area (SOA)

[1] E. Ojefors, J. Grzyb, Y. Zhao, B. Heinemann, B. Tillack, and U. R. Pfeiffer, "A 820GHz SiGe chipset for terahertz active imaging applications," in Solid-State Circuits Conference Digest of Technical Papers (ISSCC), 2011 IEEE International. IEEE, Feb. 2011, pp. 224–226.

# Outline

1. Introduction
2. Experimental Setup
3. System Validation
4. Results and Discussion
5. Extraction of  $C_{TH}$
6. Measurement vs simulation
7. Conclusions

# 1. Introduction

## Parameters

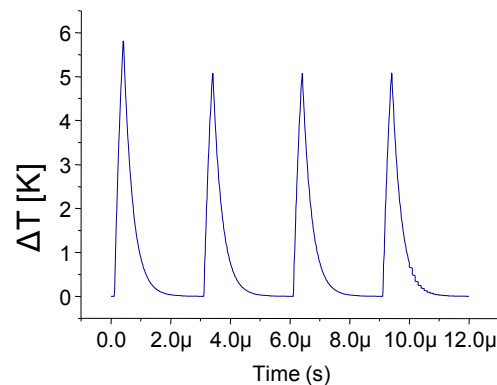
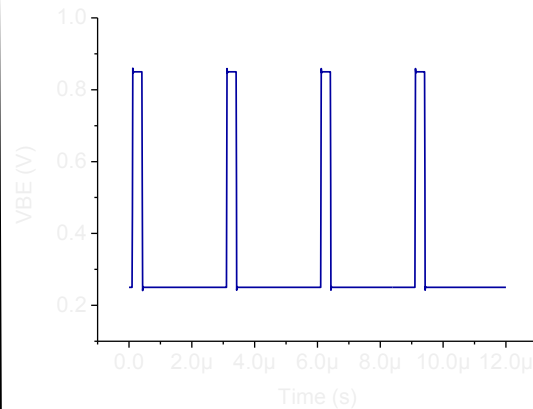
- Duty cycle  $D$
- Pulse width  $T_w$
- Pulse period  $T_p$

$$D = \frac{T_p}{T_w} \cdot 100$$

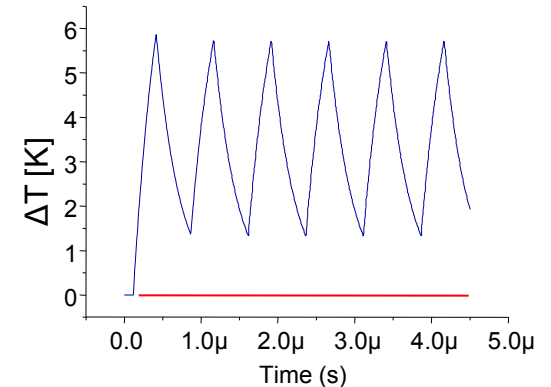
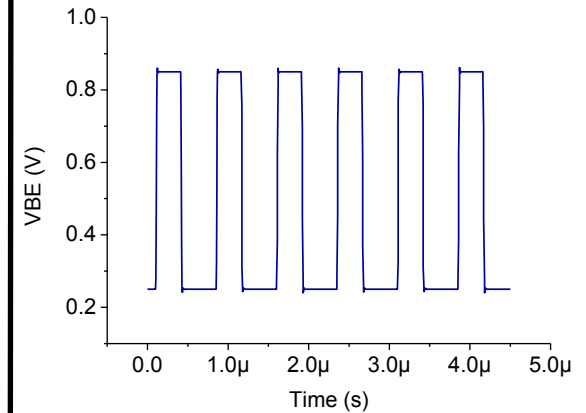
- Generally:  
 $0.1\% < D < 10\%$

**Trade-off isothermal  
behavior and  
measurement  
accuracy**

### Small duty-cycle



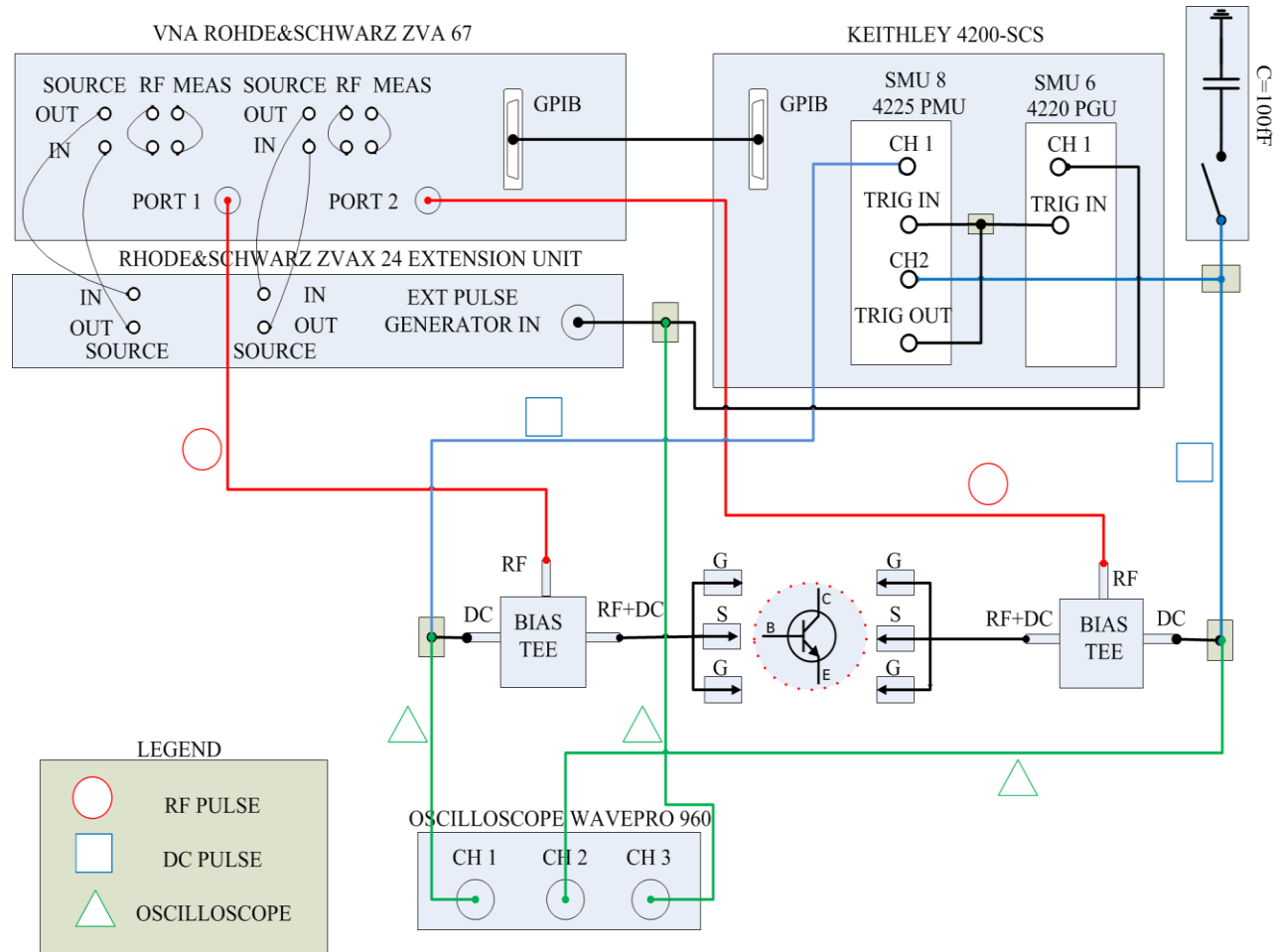
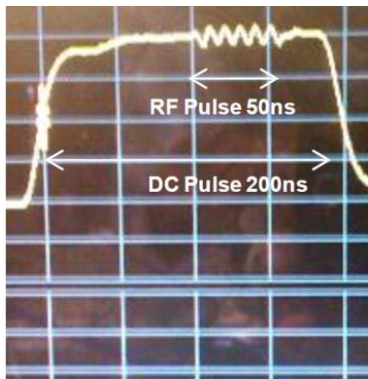
### High duty-cycle



# 2. Experimental Setup

## Pulsed measurement system characteristics:

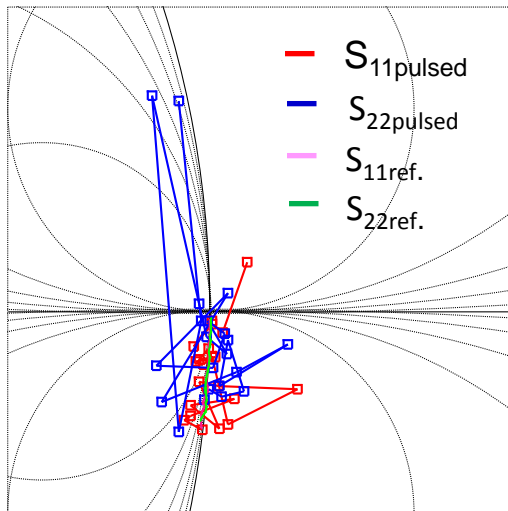
- Pulse width  
 $T_{w_{min}} \geq 80ns$  DC  
 $T_{w_{min}} \geq 100ns$  RF
- $T_{rise}$  and  $T_{fall} \geq 20ns$
- Frequency  
 $f$  [500MHz – 45GHz]
- Duty-Cycle  
 $D$  [0.01% - 50%]
- Current resolution [ $\mu A$ ]



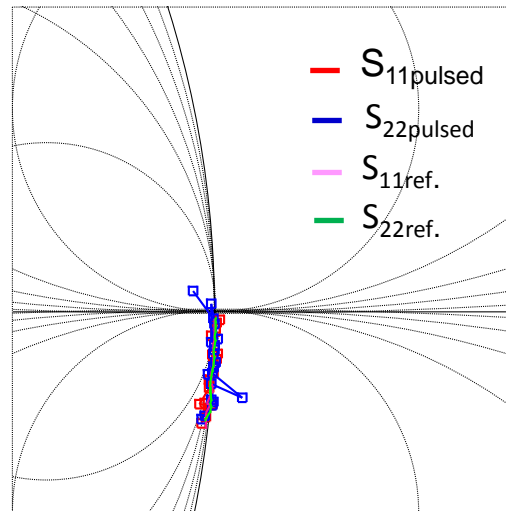
# 3. System Validation

## Measurement of an OPEN (4.5fF) with $f$ [500MHz – 45GHz]

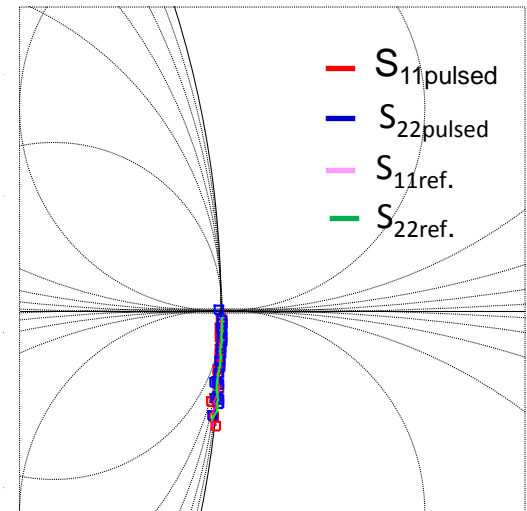
Duty cycle= 0.1%



Duty cycle= 1%



Duty cycle= 5%

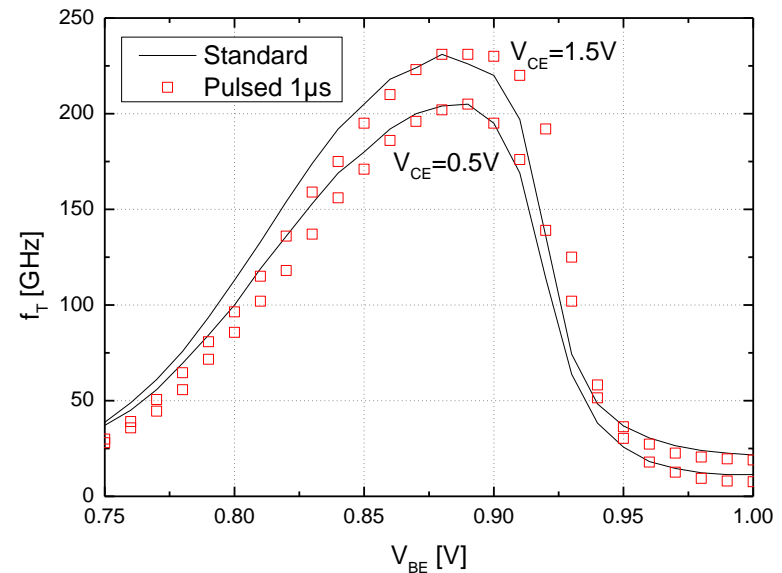
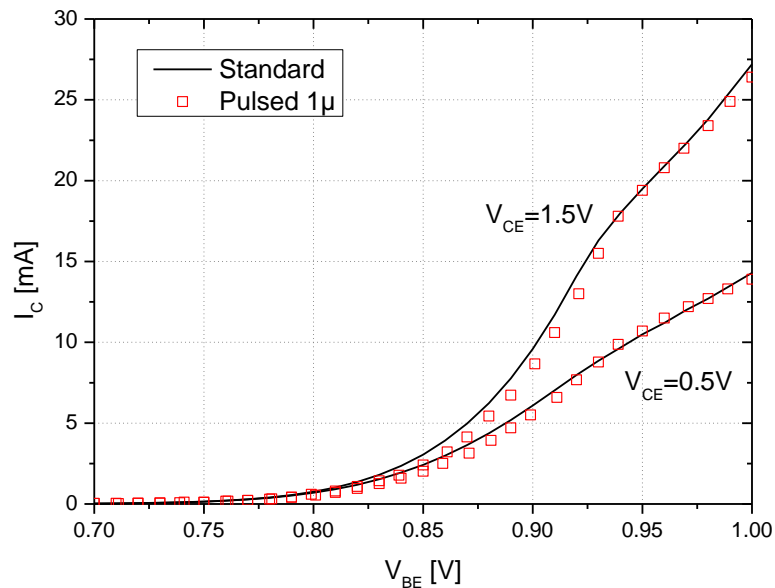


Using D of 5% conventional and pulsed S-parameter measurement are in very good agreement

## Transistor measurement of a SiGe HBT

Technology process of STMicroelectronics:  $f_T=230\text{GHz}$   $f_{\max}=290\text{GHz}$

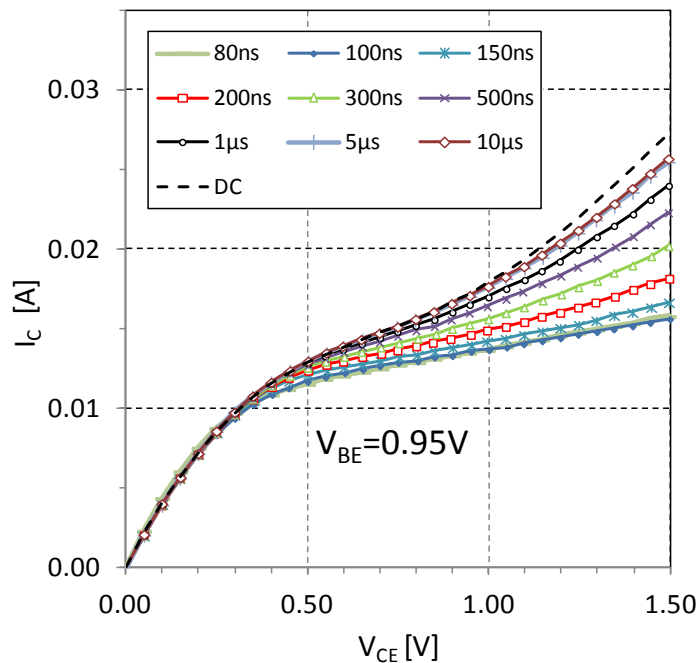
Device geometry:  $W_E=0.23\ \mu\text{m}$   $L_E=5.0\ \mu\text{m}$



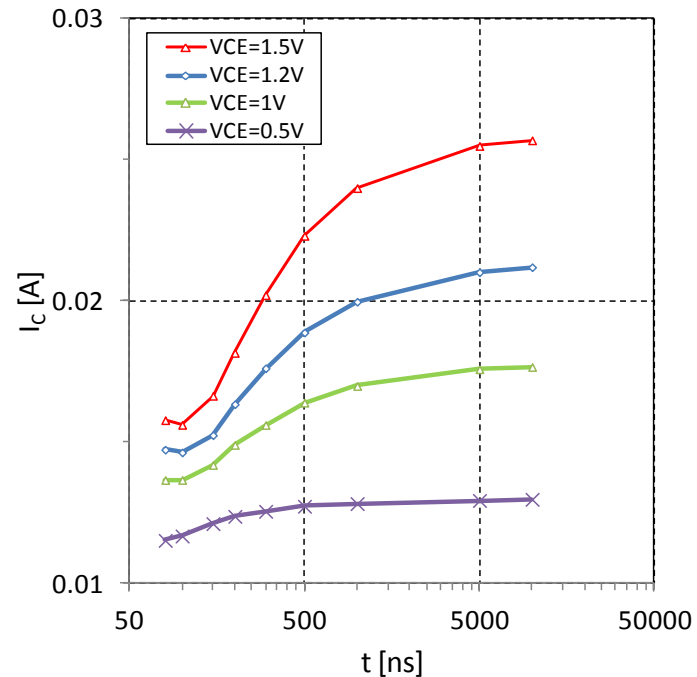
Pulsed I(V) and pulsed RF characteristics in good agreement with conventional measurements

# 4. Results and Discussion

## Pulsed I(V) for SiGe HBT with $W_E = 0.27 \mu\text{m}$ $L_E = 5.0 \mu\text{m}$



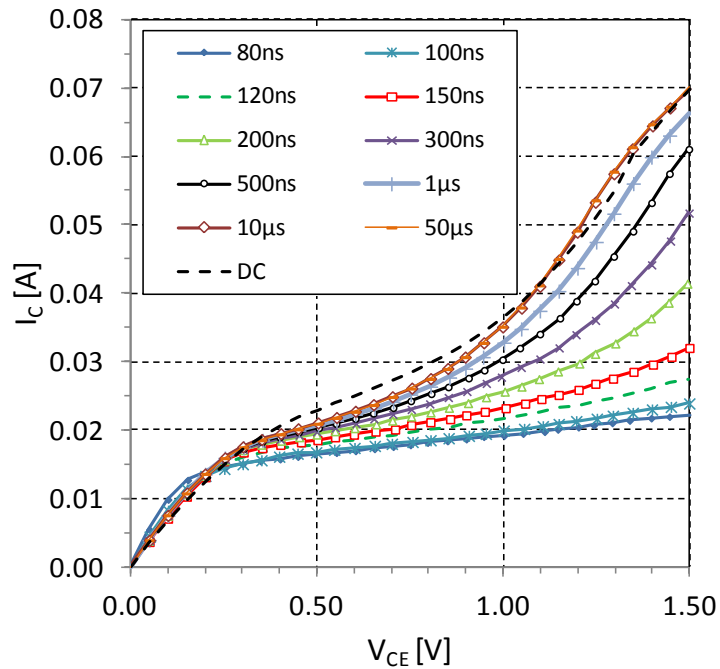
Collector current  $I_C$  vs. collector emitter voltage  $V_{CE}$



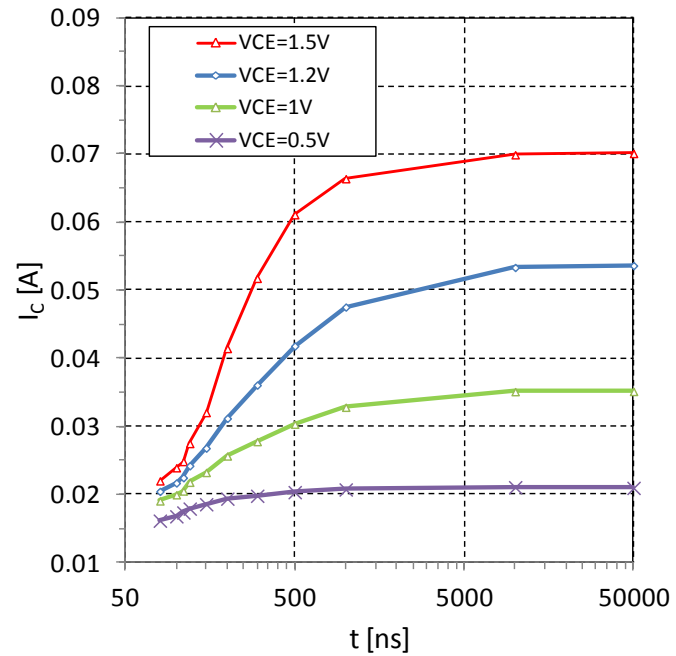
Collector current  $I_C$  vs. pulse width  $t$



## Pulsed I(V) for SiGe HBT with $W_E = 0.84 \mu\text{m}$ $L_E = 5.0 \mu\text{m}$

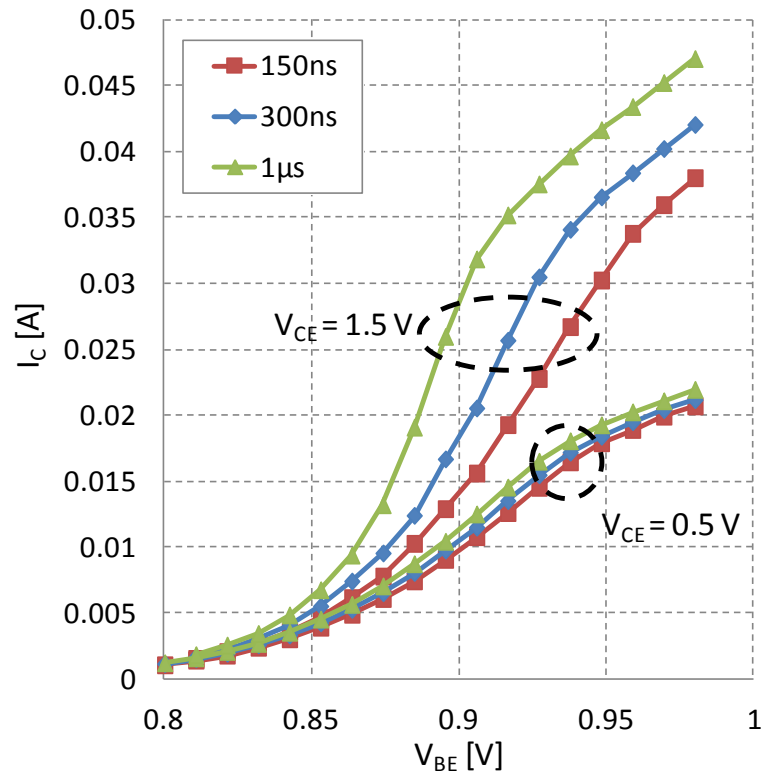


Collector current  $I_C$  vs. collector emitter voltage  $V_{CE}$

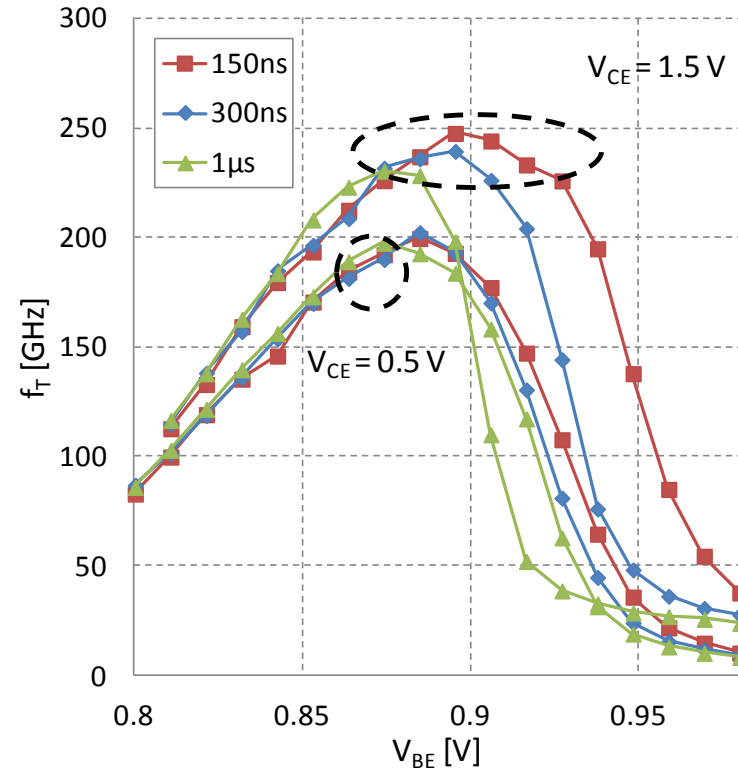


Collector current  $I_C$  vs. pulse width  $t$

## Pulsed I(V) and pulsed RF for SiGe HBT with $W_E = 0.84 \mu\text{m}$ $L_E = 5.0 \mu\text{m}$

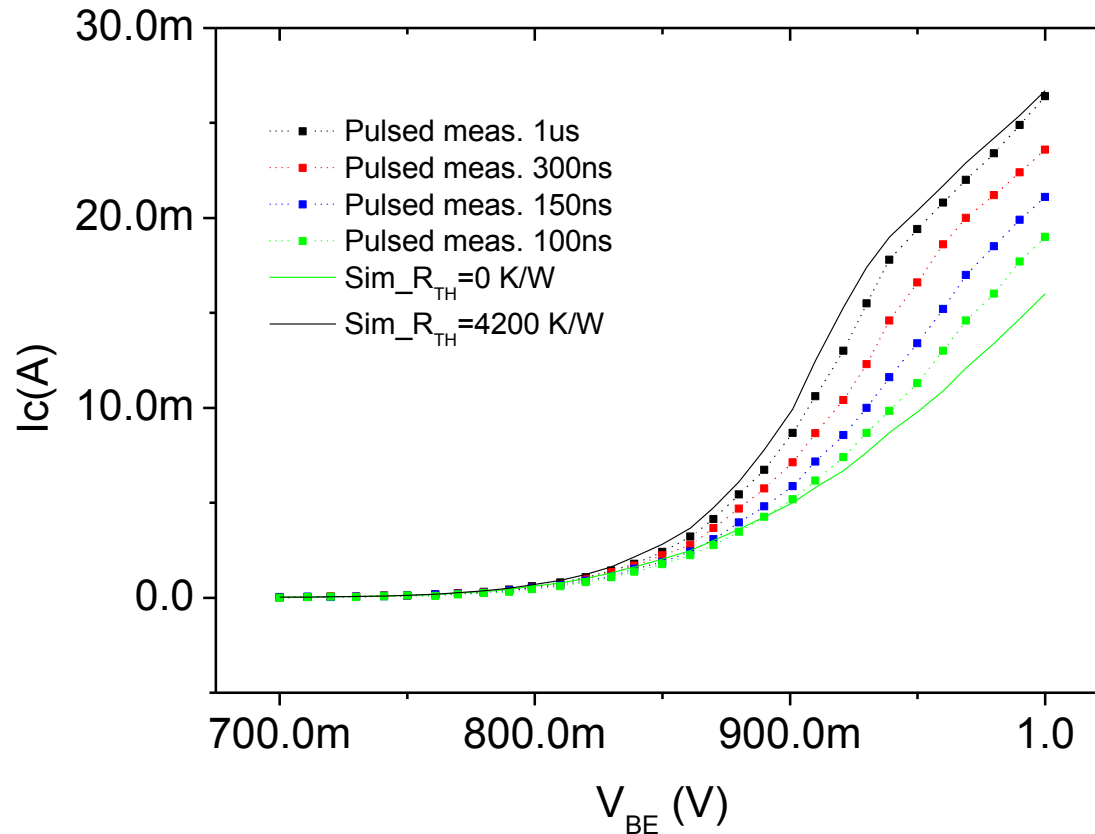


Collector current  $I_C$  vs.  
base emitter voltage  $V_{BE}$



Transit frequency  $f_T$  vs.  
base emitter voltage  $V_{BE}$

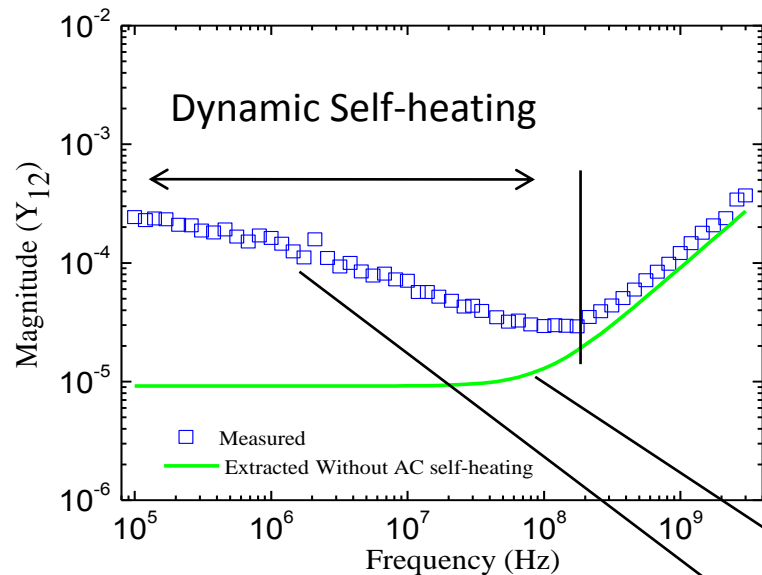
## Isothermal measurement?



For a pulse width of 100ns self-heating has been significantly reduced

# 5. Extraction of $C_{TH}$

## A) $C_{TH}$ extraction from low freq. Y-parameters



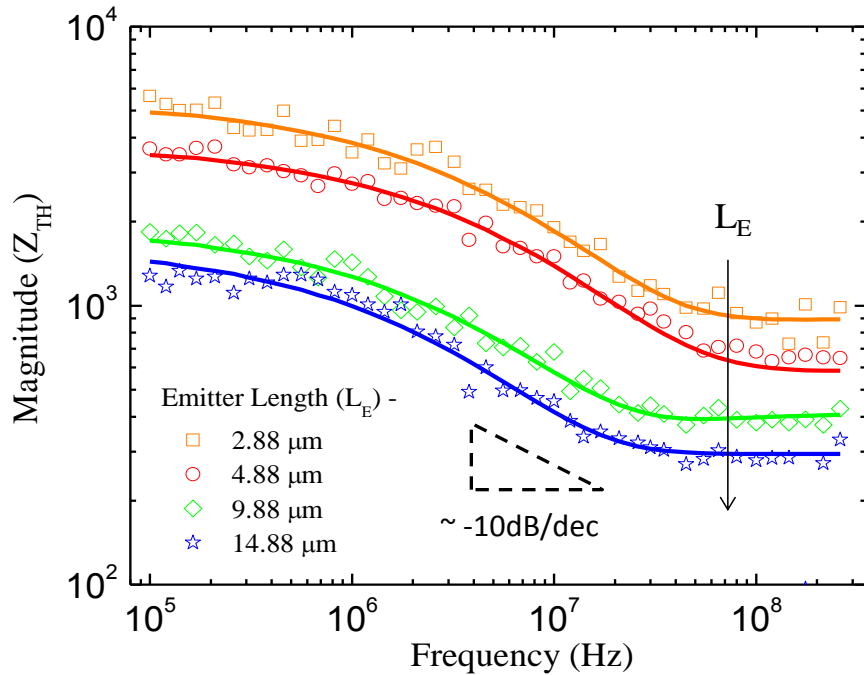
□ Low frequency S-parameter measurements :

- 100 kHz – 3 GHz,
- $V_{CE} = 1.5$  V
- $V_{BE} = 0.95$  V

□ DUT :  $L_E * W_E = 9.88 * 0.15$   $\mu\text{m}^2$

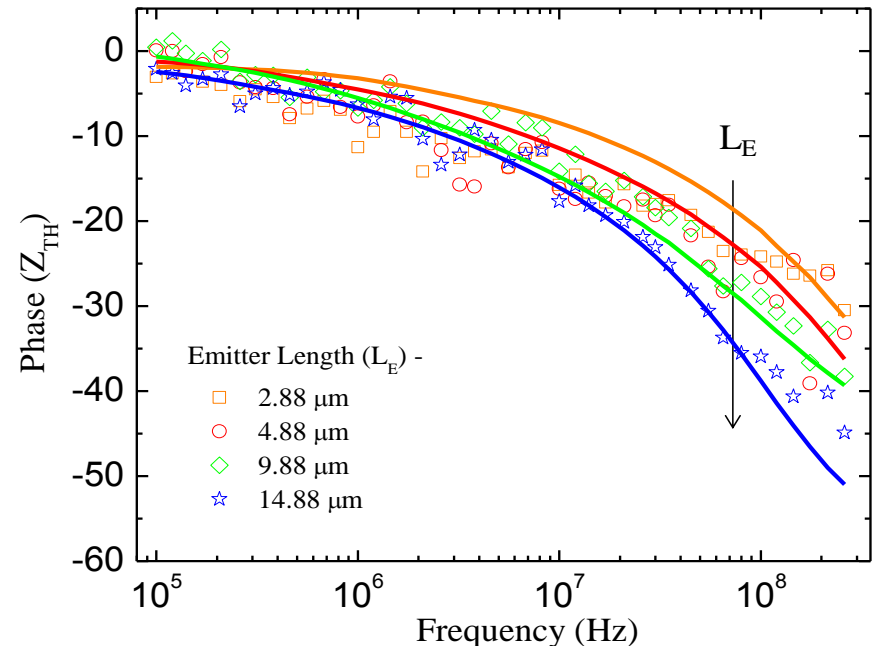
Normalized Thermal Impedance  $\rightarrow$

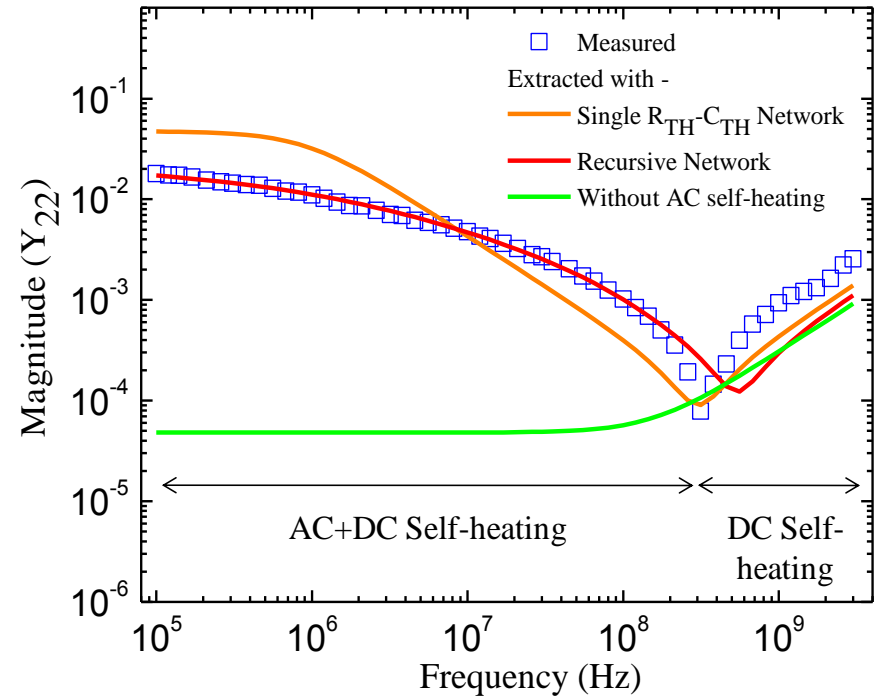
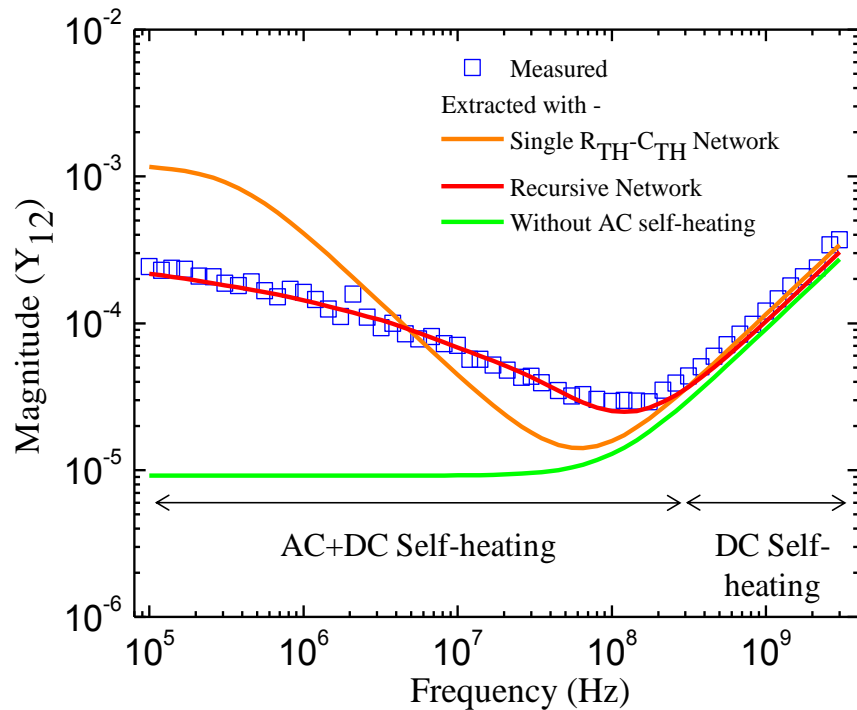
$$Z_{TH}(\omega) = \frac{(y_{12}(\omega) - y_{12}^{AC})}{(y_{12}^{DC} - y_{12}^{AC})} \cdot \frac{(I_C + V_{BE} y_{12}^{DC} + V_{CE} y_{22}^{DC})}{(I_C + V_{BE} y_{12}(\omega) + V_{CE} y_{22}(\omega))}$$



- Symbols – measured
- Lines – extracted with Recursive electro-thermal network

▪ Frequency domain magnitude and phase of thermal impedance for different geometry of transistor



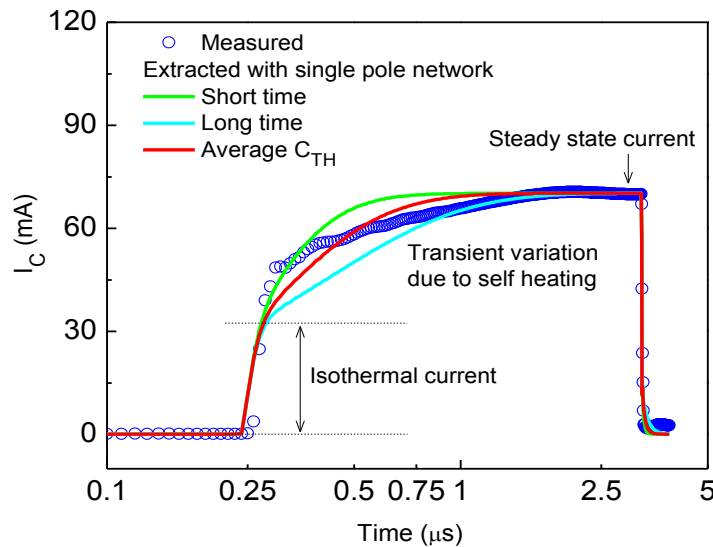


Comparison of thermal modeling of y-parameters with HiCuM compact model simulation connecting the electro-thermal network at temperature node:

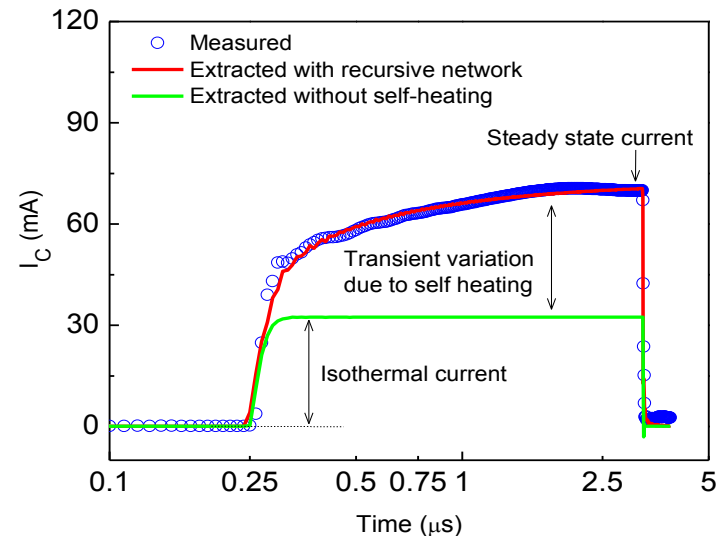
1. Single R-C network, 2. Recursive network and 3. only with Thermal resistance

## B) From Pulsed I(V) Measurements

Comparison between measurements and HiCuM L2 simulation. ( $A_E = 15 \times 0.27 \mu\text{m}^2$ )

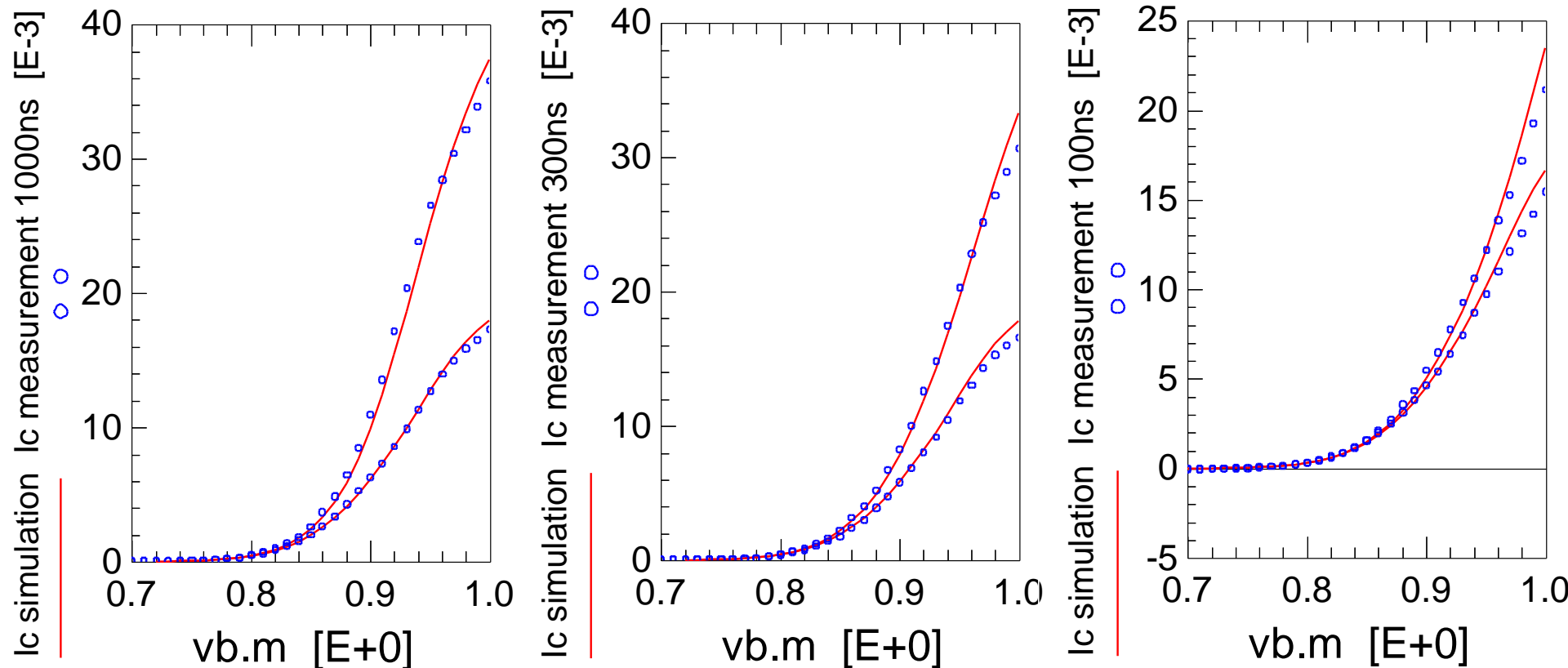


Thermal modeling with single pole network



Thermal modeling with recursive network

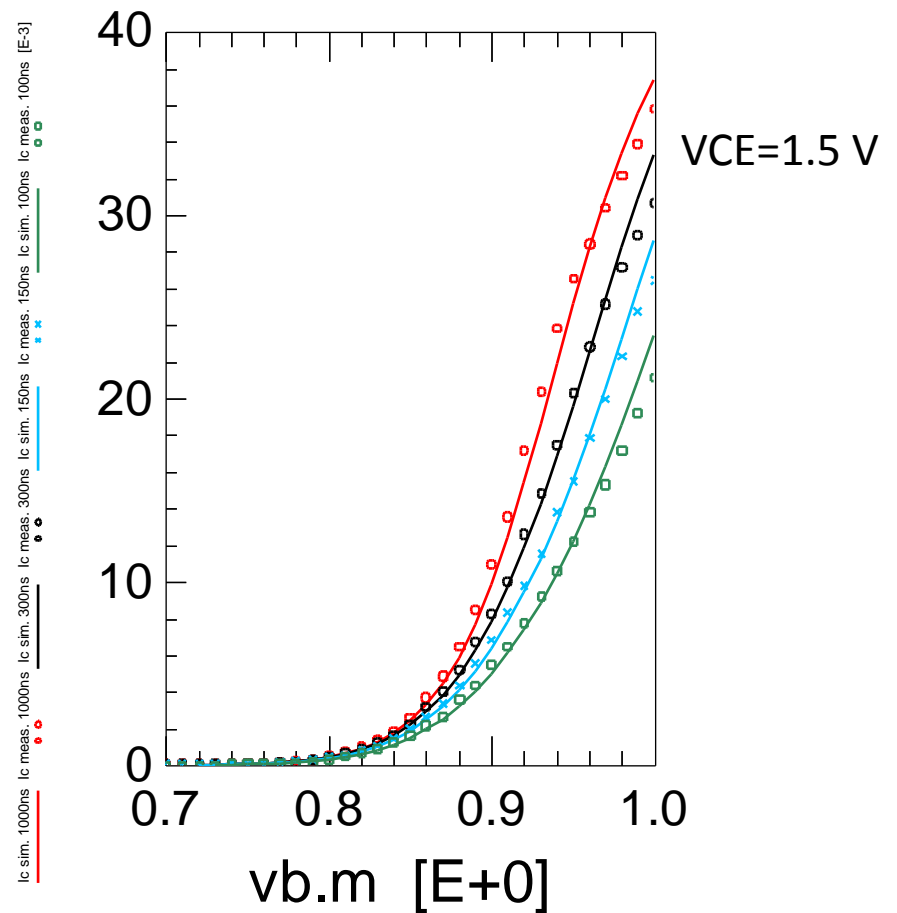
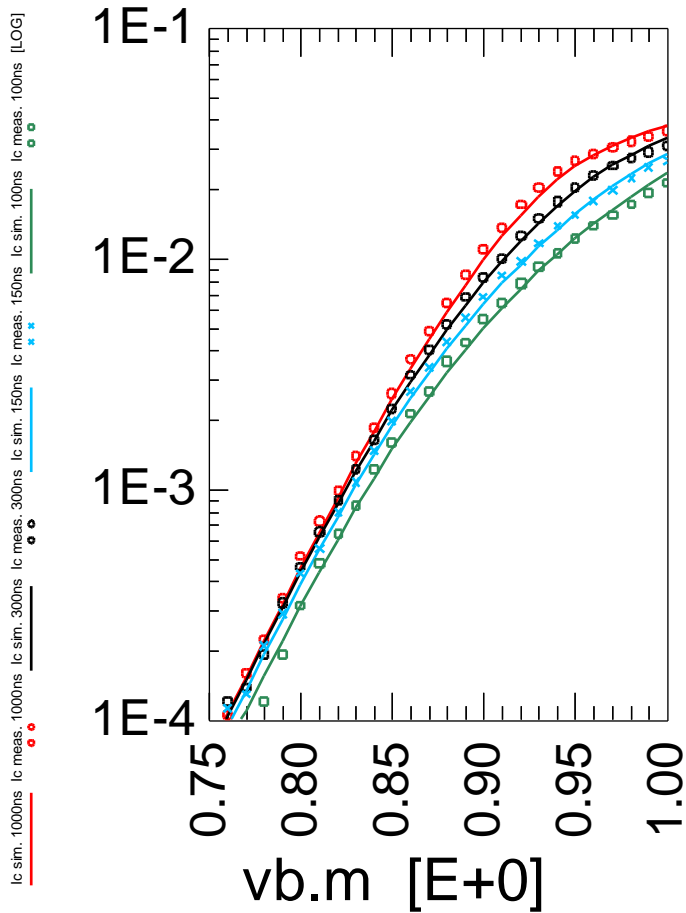
# Measurement vs simulation (1/3)



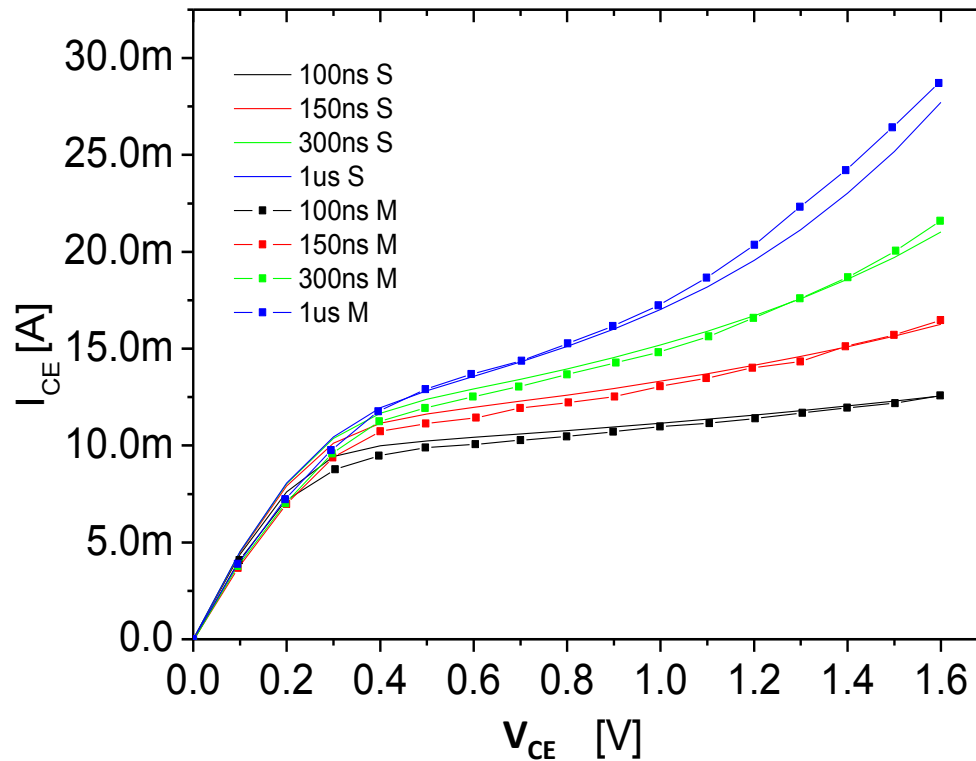
VCE=0.5V & 1.5V



# Measurement vs simulation (2/3)



# Measurement vs simulation (3/3)



# 6. Conclusions

- State of the Art Pulsed I(V) pulsed RF System validated with conventional measurements
- Self-heating can be significantly decreased and SOA expanded
- Pulsed measurements help separating thermal effects from electrical effects (e.g. Self heating  $\leftrightarrow$  Avalanche)
- Extraction procedure to achieve physical model parameters is much easier

# Acknowledgment

The Authors would like to thank STMicroelectronics for supplying the wafers as well as RF2THZ project.